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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 213.007-US)In the Application of: **YE ET AL.**Serial No: **10/816,573**Filed: **APRIL 1, 2004**Title: **SYSTEM AND METHOD OF LITHOGRAPHY
SIMULATION**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450) Group Art Unit: **1756**

) Before Examiner:

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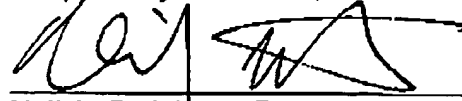
STATEMENT OF RELATED APPLICATIONS

Dear Sir:

The above-referenced application is related to the following applications:

1. "System and Method of Lithography Simulation ", Serial No. 10/981,914,
filed November 4, 2004 (still pending);
2. "System and Method of Lithography Simulation ", Serial No. 10/989,972,
filed November 16, 2004 (still pending);
3. "System and Method of Lithography Simulation ", Serial No. 11/024,121,
filed December 28, 2004 (still pending); and
4. "System and Method of Lithography Simulation ", Serial No. 11/037,988,
filed January 18, 2005 (still pending).

Respectfully submitted,



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Date: February 3, 2005